## UNIVERSITY OF CALIFORNIA College of Engineering Department of Electrical Engineering and Computer Sciences

EE 130 / EE 230A Fall 2013 Prof. Liu

# Homework Assignment #5

Due at the beginning of class on Thursday 10/3/13

## **<u>Problem 1</u>**: Schottky diode *I-V* characteristics

A Schottky diode maintained at T = 300 K is formed between NiSi (which is employed in the most advanced CMOS technologies today) and silicon doped with  $10^{16}$  cm<sup>-3</sup> phosphorus. The cross-sectional area is  $100 \ \mu m \times 100 \ \mu m = 10^{-4} \text{ cm}^2$ .

- (a) Determine the reverse saturation current  $I_{\rm S}$ , using the measured value of Schottky barrier height given in Lecture 7 (Slide 8). Recall from Lecture 4 that the <u>conductivity</u> effective masses for electrons and holes in silicon are  $0.26m_0$  and  $0.39m_0$  (where  $m_0 = 9.1 \times 10^{-31}$  kg) respectively.
- (b) Plot *I vs.*  $V_A$  on a semi-log plot (*i.e. I* on a log scale and  $V_A$  on a linear scale), for  $V_A$  in the range from 0.05 V to 0.4 V. At what value of  $V_A$  does I = 1 mA? (This is a typical level of current.)

## **Problem 2: Practical ohmic contact**

Consider a MS junction formed by NiSi in contact with uniformly doped silicon, maintained at T = 300K. This junction can pass significant current with a small bias ( $V_A \neq 0$  V) by quantum-mechanical tunneling of majority carriers into the silicon, if the barrier seen by the carriers is sufficiently narrow, *i.e.* if the junction depletion width W is less than 10 nm.

- (a) What is the minimum value of  $N_D$  such that this condition is met for a NiSi contact to n-type Si? (From Lecture 7 Slide 8, the Schottky barrier height for electrons,  $\Phi_{Bn}$ , is 0.65 eV.) You may assume that  $qV_{bi} \cong \Phi_{Bn}$ , as shown in Lecture 8 Slide 7.
- (b) What is the minimum value of  $N_A$  such that this condition is met for a NiSi contact to p-type Si? (From Lecture 7 Slide 8 the Schottky barrier height for holes,  $\Phi_{Bp}$ , is 0.47 eV.) You may assume that  $qV_{bi} \cong \Phi_{Bp}$ .
- (c) Considering your answers to (a) and (b), is it easier to form a practical ohmic contact to p-type or n-type silicon? Why?

#### **Problem 3: Contact resistance**

- (a) Typically, the specific contact resistivity,  $\rho_c$ , for a silicide contact to heavily doped silicon is ~10<sup>-8</sup>  $\Omega$  cm<sup>2</sup>. In the most advanced CMOS technologies today, the area ( $A_c$ ) of a silicide contact to the heavily doped source and drain regions of a MOSFET can be as small as  $3F^2$ , where *F* is the minimum half-pitch. Calculate the contact resistance  $R_c = \rho_c/A_c$  of such a minimum-sized contact, for F = 22 nm (relevant to Intel's most advanced CMOS technology). Is the contact resistance significant compared to the intrinsic Si MOSFET on-state resistance which is ~10 k $\Omega$ ?
- (b) Compound semiconductor materials such as GaAs eventually may be used in n-channel field-effect transistors for digital logic applications, due to their higher electron mobility (corresponding to a lower conductivity effective mass) as compared against Si. A practical technological challenge is achieving low source/drain-contact resistance to n-type GaAs, however. Considering that the electron affinity of GaAs is similar to that of Si, and that the solid solubility of n-type dopants (donors) is ~100× lower than in Si, explain why this is the case.

#### **<u>Problem 4</u>**: pn junction electrostatics

Consider a silicon step junction maintained at T = 300K under equilibrium conditions (*i.e.* with zero applied voltage) with p-side doping  $N_{\rm A} = 1 \times 10^{16}$  cm<sup>-3</sup> and n-side doping  $N_{\rm D} = 1 \times 10^{17}$  cm<sup>-3</sup>. a) Calculate the built-in voltage,  $V_{\rm bi}$ .

b) Calculate the depletion region width, W. What are  $x_p$  and  $x_n$ ?

Note that 
$$x_p = \frac{N_D}{N_A + N_D} W$$
 and  $x_n = \frac{N_A}{N_A + N_D} W$ 

c) What is the electrostatic potential at x = 0 (*i.e.* how much voltage is dropped across the p-side)?

Note that 
$$V(0) = \frac{qN_A}{2\varepsilon_s} x_p^2 = V_{bi} - \frac{qN_D}{2\varepsilon_s} x_n^2$$

d) Calculate the peak electric field (at x = 0):  $\mathcal{E}(0) = \frac{2V_{bi}}{W}$ 

- e) Using the values obtained in (a)-(d), sketch the charge density distribution  $\rho(x)$ , electric field distribution  $\mathcal{E}(x)$ , and electrostatic potential V(x).
- f) Show qualitatively (on your sketches from (e)) how an applied forward bias ( $V_A > 0$  V) affects the depletion region width *W*, the voltage dropped across the depletion region, and the peak electric field  $\mathcal{E}(0)$ .